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FOR IMMEDIATE RELEASE

UC SANTA BARBARA NANOFABRICATION FACILITY AND PLASMA-THERM HOST PLASMA PROCESSING TECHNICAL WORKSHOP

St. Petersburg, Florida, October 16, 2012 – Plasma-Therm has provided an advanced two day plasma processing workshop at UC Santa Barbara’s Nanofabrication Facility. Presentations addressed both fundamental and advanced plasma etching and deposition technologies used primarily in semiconductor device fabrication and materials science research. The UCSB facility, part of NNIN (National Nanofabrication Infrastructure Network), provides resources for both academic and industrial users and attracts researchers from throughout the world. The more than 70 participants consisted of graduate students, facility staff, post-doctoral researchers and engineers from multiple disciplines, and included attendees from 15 local companies ranging from start-ups to Fortune 500. This technology community outreach event attracted researchers involved in projects requiring process capability spanning a broad range of cutting edge research topics as diverse as solar energy, nanostructures, IR imaging, opto-telecommunications, and MEMS. Plasma-Therm, a leading semiconductor plasma processing equipment supplier, has held similar one and two day workshops at prominent universities and institutions such as Stanford, Harvard, Cornell IMRE (Singapore), Lund University (Sweden), and the Institute of Semiconductors of the Chinese Academy of Sciences (Beijing),

Dr. Brian Thibeault, Senior Process Scientist at UCSB’s Nanofabrication Facility commented that, “At the Plasma-Therm workshop on plasma processes, Dr. Lishan provided our user community with a great foundation for understanding and improving their plasma etching and deposition processes. The breadth of material presented was excellent, giving our user community fundamental understanding of plasma processes and practical advice for robust process development. As the senior process scientist in the facility this makes my job much easier when interacting with and advising users of plasma-based systems. I would highly recommend this educational workshop to all academic research laboratories.”

“This well attended two day workshop provided researchers a broad, but concentrated, forum to quickly gain insight into plasma processing” explained Dr. David Lishan, Plasma-Therm Principal Scientist and organizer of the workshop series. “We continue to be pleased with the response to this event and are privileged to have these opportunities for interaction with those leading today’s R&D efforts in a

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variety of disciplines. These two day events allow time for topics often not formally taught and improves upon the traditionally lengthy trial and error learning process. This is especially true for commercial fabs where training is often difficult to come by. Drawing researchers and engineers from 15 different companies in this active technology community is very satisfying.”

About UC Santa Barbara Nanofabrication Facility

UCSB has extensive facilities and research in nanotechnology, and currently supports approximately 600 unique researchers. Specific UCSB strengths include leading expertise in compound semiconductors, photonics, quantum structures, and expertise with non-standard materials and fabrication processes. The UCSB research community is highly collaborative, involving Materials Science, Chemistry, Physics, Biology, and Chemical, Electrical, and Mechanical Engineering. Areas of excellence include: compound semiconductor electronic and optoelectronic devices in GaAs, InP and the semiconductor nitrides; polymer and organic electronic and photonic devices; quantized electron structures and THz physics; spintronics, single electronics, and quantum computation; quantum optics; MEMS/NEMS, bio-instruments, and microfluidics.



Plasma-Therm Technical Workshop at UCSB

The Nanofabrication Facility, with a comprehensive set of advanced semiconductor processing equipment in a nearly 13,000 sq. ft cleanroom facility, is one of the most fully equipped university facilities in the world. Recent installation of a JEOL 6300, 100kV system capable of writing sub-10nm features provides additional nanometer-scale R&D capability. On-site and remote support of users (equipment training, process consultation, and remote job processing) is supplied is supplied with a staff of 11 engineers.

About Plasma-Therm

Established in 1974, Plasma-Therm is a U.S. manufacturer of advanced plasma processing equipment focusing on research and development systems to high volume production in specialty semiconductor markets including solid state lighting, power, data storage, renewable energy, MEMS, nanotechnology, photonics, and wireless communication. They offer leading etching and deposition technologies and solutions for these markets. Sales and service locations throughout North America, Europe and Asia-Pacific, meet the diverse needs of Plasma-Therm’s global customer base. For further information please visit www.plasmatherm.com.

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